AOI ELECTRONICS CO.,LTD.

<Analysis Equipment List>

AOI is equipped with the following analysis devices, and skilled engineers are engaging to develop new techniques and evaluating the products.

No.	Use	Device name	Maker name
1	Form observation／Image observation	Metallurgical microscope	Olympus
2		IR microscope	Olympus
3		Laser displacement meter	KEYENCE
4		Digital microscope	HIROX
5		Measurement microscope	NIKON
6		CNC Vision Measuring System	Mitutoyo
7		Scanning Electron Microscope（SEM）	JEOL
8		Schottky Field Emission Scanning Electron Microscope（FE-SEM）	JEOL
9		High-precision non-contact depth measuring microscope	Union Optical
10	Component analysis	ICP emission spectrometry analyzer	Hitachi High-Tech Science
11		Energy Dispersive X-ray Spectrometer（EDS）	JEOL
12		Fourier Transform InfraRed Spectrometer（FT-IR）	PerkinElmer Japan
13		FT-IR Imaging System	PerkinElmer Japan
14	Structure analysis／Non Destructive Inspection	X-ray(XRF) Coating Thickness Gauges	Hitachi High-Tech Science
15		Contact angle measuring instrument	ERMA
16		Microfocus X-Ray Inspection Systems	SHIMADZU
17		Micro focus 3D X-ray CT system	U.H.SYSTEM
18		Scanning Acoustic Tomograph（SAT）	Hitachi Power Solutions
19	Electrical measurement	Semiconductor Curve Tracer	IWATSU
20		Open short tester	HANWA ELECTRONIC
21	Materials strength／Properties of matter analysis	Distortion measuring instrument	KYOWA ELECTRONIC INSTRUMENTS
22		Spectrophotometer	SHIMADZU
23		Barcol hardness tester	Barber Colman
24	Precision processing equipment	Ion milling system	Hitachi High-Technologies
25		Grinding and polishing machine	Struers
26	Decapsulation	Failure Analysis Laser Inspection Tool	Control Laser
27		Draft chamber	Enya factory

<Field Emission Scanning Electron Microscope(FE-SEM)>
<Energy dispersive X-ray spectrometry(EDS)>

<Fourier Transform Infrared Spectrometer(FT-IR)>
<Infrared Imaging System>

<Failure Analysis Laser Inspection Tool>

<Micro focus 3D X-ray CT system>